

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 1821**  
Mitsuhiro OKUNE et al. : Attorney Docket No. 2006\_0772A  
Serial No. 10/581,256 : Group Art Unit 1792  
Filed May 31, 2006 : Examiner Mahmoud Dahimene  
PLASMA ETCHING METHOD : **Mail Stop AF**

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**AMENDMENT UNDER 37 CFR § 1.116**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Responsive to the Office Action mailed December 24, 2008, please amend the above-identified application as follows.

TABLE OF CONTENTS

	<u>SECTION</u>	<u>PAGE</u>
I.	Amendments to the claims	2
II.	Remarks	5